

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Kazuya Hizawa

Group Art Unit: Unknown

Continuation of Serial No. 10/283,189

Examiner: Unknown

Filed: February 19, 2004

For: A METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE HAVING A
METALLIC SILICIDE LAYER

INFORMATION DISCLOSURE STATEMENT
(SUBMISSION WITH CONTINUATION-IN-PART OR
RULE 1.53(b) CONTINUATION OR DIVISIONAL APPLICATION)

U.S. Patent and Trademark Office
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Date: February 19, 2004

Sir:

Pursuant to 37 C.F.R. §§ 1.97 and 1.98, Applicant hereby submits an
Information Disclosure Statement for consideration by the Examiner.

I. **LIST OF PATENTS, PUBLICATIONS OR OTHER INFORMATION**

The patents, publications or other information submitted for consideration by the
Office are listed on PTO-1449 form(s), attached hereto.

II. **REFERENCES PREVIOUSLY CITED OR SUBMITTED**

Pursuant to 37 C.F.R. § 1.98(d), consideration of information listed on the PTO-
1449 form(s) is requested since any patents, publications or other information which are
listed on the PTO-1449 form(s) but for which copies are not enclosed herewith, were
previously cited by or submitted to the PTO in one of the following applications which
has been relied upon for an earlier filing date under 35 U.S.C. § 120:

U.S. Serial Number

10/283,189

U.S. Filing Date

October 30, 2002

III. FEES


This Information Disclosure Statement is being filed concurrent with the filing of a continuation-in-part, continuation or divisional patent application; therefore, no fee is required.

If the Examiner has any questions concerning this IDS or requires a copy of any of the references cited but not provided, he/she is requested to contact the undersigned. If it is determined that this IDS has been filed under the wrong rule, the PTO is requested to consider this IDS under the proper rule (with a petition if necessary) and charge the appropriate fee to Deposit Account No. 50-0238.

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 50-0238 for any additional fee required under 37 C.F.R. §§ 1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

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Enclosure: PTO-1449 Form

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) OKI.390C		Application Number NEW		
				Applicant(s) Kazuya Hizawa				
				Filing Date February 19, 2004		Group Art Unit Unknown		
U.S. PATENT DOCUMENTS								
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	A	2002/0061639	05/2002	Itonaga				
	B	6,054,386	04/2000	Prabhakar				
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
	C	2000-082811	03/21/2000	Japan				
	D	10-335261	12/18/1998	Japan				
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>								
	E	J. Fukuhara et al., "The Orientation of Blanket W-CVD on the underlayer Ti/TiN studied by XRD," ADMETA 2000: Asian Session, pages 71 and 72.						
	F	Kunihiro Fujii et al., "Sub-Quarter Micron Titanium Salicide Technology With In-Situ Silicidation Using High-Temperature Sputtering," 1995 Symposium on VLSI Technology Digest of Technical Papers, pages 57 and 58.						
EXAMINER				DATE CONSIDERED				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								